

RECEIVED  
CENTRAL FAX CENTER

JUN 23 2004

OFFICIAL

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Yi-Nien Su

Group Art Unit: 1765

Serial No.: 10/077,720

Examiner: Anita Karen Alanko

Filed: 02/15/2002

In Response to Office Action  
Dated: March 23, 2004

For: A METHOD FOR IMPROVED PLASMA ETCHING CONTROL

Attorney Docket No.: 67,200-478

OK  
to  
enter  
after  
7/11/04

Certificate of Facsimile Transmission

I hereby certify that this paper (along with any referred to as being attached or enclosed) is being deposited with the United States Patent Office on the date shown below via facsimile no. (703) 872-9311

Date: June 23, 2004

  
Kathy Dixon

REQUEST FOR RECONSIDERATION

Commissioner for Patents  
P.O. Box 1450  
Alexandria, Va 22313-1450

Dear Sir:

In response to a final Office Action mailed March 23, 2004, please enter the following amendments and consider the following remarks.